

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**INFORMATION DISCLOSURE STATEMENT**

APPLICANT(S): Shimichiro Nohdo DOCKET NO.: 09792909-5846

SERIAL NO.: 10/812,602 GROUP ART UNIT: 2112

DATE FILED: March 30, 2004 EXAMINER: Rebecca Slomski

INVENTION: WAFER, EXPOSURE MASK, METHOD OF DETECTING MARK, AND  
METHOD OF EXPOSURE

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

SIR:

In accordance with the provisions of 37 C.F.R. § 1.56, Applicants request that citation and examination of the references identified on the attached PTO-SB08A form, in accordance with 37 C.F.R. §1.98, be made during the course of examination of the above-referenced application for United States Letters Patent. These references were cited in an Office Action issued on November 14, 2006, in connection with Japanese application no. JP2003-097625. Copies of the foreign references and machine translations are attached as is a copy of the Japanese office action.

Respectfully submitted by,

/David R. Metzger/ (Reg. 32,919)

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